

*a clear edge*

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**Abatement of N<sub>2</sub>O from  
Semiconductor Manufacturing**



Vacuum science... product solution.

# Confidentiality Statement

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# Overview – N<sub>2</sub>O Abatement

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- N<sub>2</sub>O is a Greenhouse Gas
- N<sub>2</sub>O can be abated
  - N<sub>2</sub>O lab tests
    - Byproducts
- Caveats
  - Emission factors
  - Complex process recipes



## N<sub>2</sub>O Emissions from the Fab

- Nitrous oxide (N<sub>2</sub>O) is used as a process gas in CVD and diffusion
  - Benign and stable
  - A Greenhouse Gas that accumulates in the atmosphere
- N<sub>2</sub>O accounts for ~5% of all process-related GHG emissions from US Semi manufacturing\*
- N<sub>2</sub>O by-products include NO, NO<sub>2</sub>
  - NO<sub>x</sub> leads to acid rain

\*In tons of CO<sub>2</sub> equivalents

Source: Per EPA 2012 GHG emissions summary. N<sub>2</sub>O 100 yr GWP 298 (vs. CF<sub>4</sub>, 7390; SF<sub>6</sub>, 22,800)



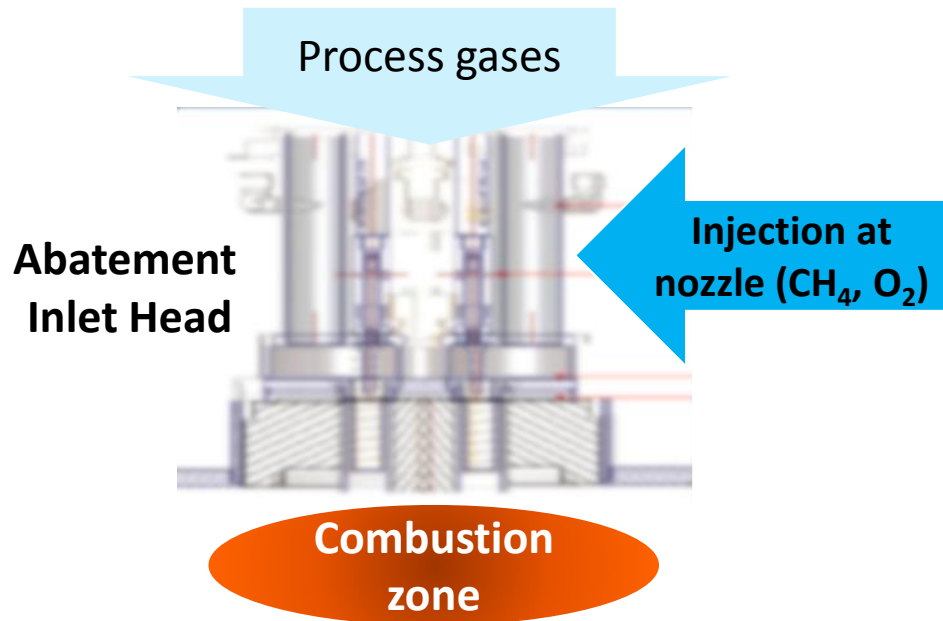
# N<sub>2</sub>O Abatement Project - SEMATECH sponsored

- – Can N<sub>2</sub>O be abated?
  - Excellent DRE in lab
    - N<sub>2</sub>O flow at 10 slm
- Edwards Atlas Kronis abatement
  - Porous ceramic inward-fired combustor
  - CH<sub>4</sub> and/or O<sub>2</sub> added as needed for process recipe
    - Configurable based on application
  - Integrated water scrubber
- Abatement of N<sub>2</sub>O is not straightforward



# Abatement Process Modes for Effective Abatement

Mode	Injection At nozzle	Combustion chemistry	Application	By product Concerns
“Clean”	None	Reducing	NF <sub>3</sub>	NO <sub>x</sub>
“Deposition”	O <sub>2</sub> , CH <sub>4</sub>	Oxidizing	Low k, NH <sub>3</sub>	PICs, NO <sub>x</sub> , VOCs
“Reducing”	CH <sub>4</sub>	Reducing	N <sub>2</sub> O	PICs



**Edwards abatement combustor can be modified to most effectively destroy targeted process gases**

## N<sub>2</sub>O Abatement – Lab Results

- 10 slm N<sub>2</sub>O from MFC
  - 50 slm N<sub>2</sub> purge from vacuum pump

Test	SiH <sub>4</sub>	Fuel	N <sub>2</sub> O in	N <sub>2</sub> O out	N <sub>2</sub> O %DRE
	slm	slm	ppm	ppm	
1	0	0	166,667	19,124	0.0
2	1	0	163,900	17,369	9.2
3	2	0	161,300	12	99.9
4	0	3	158,700	17599	8.0
5	0	4	156,300	14197	25.8
6	0	5	153,800	6886	64.0
7	0	6	151,500	3478	81.8
8	0	7	149,300	2233	88.3

- Added reducing agents, as N<sub>2</sub>O is an oxidizer
  - SiH<sub>4</sub>, CH<sub>4</sub>

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- With no additional reducing agents, N<sub>2</sub>O is unabated



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- Addition of 2 slm SiH<sub>4</sub> abates N<sub>2</sub>O better

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- Addition of natural gas works pretty well too

## Addition of $\text{SiH}_4$ or Fuel Abates $\text{N}_2\text{O}$

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- If only it were that easy ...



## How Much Fuel to Add?

- More fuel gives better DRE
  - 10 slm N<sub>2</sub>O is abated to 99% with 2 slm added silane
    - Mimics process recipes where SiH<sub>4</sub> flows with N<sub>2</sub>O

Test	SiH <sub>4</sub>	Fuel	NO out	NO <sub>2</sub> out	CO out	N <sub>2</sub> O %DRE
	slm	slm	ppm	ppm	ppm	
1	0	0	40	22	108	0.0
2	1	0	387	27	76	9.2
3	2	0	1,481	47	58	99.9
4	0	3	210	59	2231	8.0
5	0	4	523	73	1655	25.8
6	0	5	795	36	725	64.0
7	0	6	803	27	405	81.8
8	0	7	732	29	432	88.3

## How Much Fuel to Add?

- Methane addition at low flows is less expensive
  - Poor DRE, high CO generation
    - Inadequate methane – below LFL – does not combust cleanly

Test	SiH <sub>4</sub>	Fuel	NO out	NO <sub>2</sub> out	CO out	N <sub>2</sub> O %DRE
	slm	slm	ppm	ppm	ppm	
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8	0	7	732	29	432	88.3

- Similar behavior is seen with low k precursors
  - Incomplete DRE in absence of adequate fuel (Semicon West 2002, 2004)

## How Much Fuel to Add?

- High methane addition gives better DRE
  - Lower CO
  - Higher NO, not as high as with SiH<sub>4</sub>

Test	SiH <sub>4</sub>	Fuel	NO out	NO <sub>2</sub> out	CO out	N <sub>2</sub> O %DRE
	slm	slm	ppm	ppm	ppm	
1	0	0	40	22	108	0.0
2	1	0	387	27	76	9.2
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- Good performance

## How Much Fuel to Add?

- Step 1: Fuel based on N<sub>2</sub>O flow
- Step 2: Generate Look-up Table for fuel vs. N<sub>2</sub>O
  - Example:

N <sub>2</sub> O In	Fuel added	Expected Emissions			
		N <sub>2</sub> O DRE	CO, ppm	NO, ppm	NO <sub>2</sub> , ppm
2	1	98	xxx	yyy	zzz
4	---	---	---	---	---
6	+++	+++	+++	+++	+++
8	---	---	---	---	---
10	+++	+++	+++	+++	+++
15	---	---	---	---	---
20	+++	+++	+++	+++	+++
25	---	---	---	---	---

# Assigning the Correct Fuel Flow to Abate N<sub>2</sub>O

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- If only it were that easy ...





## Reaction of N<sub>2</sub>O in the Process Chamber

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- N<sub>2</sub>O is not passive in the process chamber
  - Reacts with TEOS, SiH<sub>4</sub>, low k ...
- N<sub>2</sub>O + Plasma or Heat → NO, NO<sub>2</sub>, N<sub>2</sub>, O<sub>2</sub>
  - In varying proportions
- Emissions Factors (EFs) for N<sub>2</sub>O virtually nonexistent
  - Hundreds of etch processes
  - Dozens of NF<sub>3</sub>-based cleans
- Fuel look-up table is useless without EFs

## N<sub>2</sub>O Decomposition Byproducts

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- N<sub>2</sub>O + Plasma or Heat → NO, NO<sub>2</sub>, N<sub>2</sub>, O<sub>2</sub>
- QMS required to measure N<sub>2</sub> and O<sub>2</sub>
  - N<sub>2</sub> and O<sub>2</sub> are not IR-active (cannot use FTIR)
  - N<sub>2</sub> is used for various purges
    - Pre-pump QMS is very difficult
  - N<sub>2</sub> and O<sub>2</sub> are atmospheric gases
    - Minor leaks in high vacuum of QMS have large effect
- 20 slm N<sub>2</sub>O in - maybe 15 slm N<sub>2</sub>O in exhaust
  - Or 12 slm, or 10 slm, or 8 slm
- **Cannot select fuel setting without EFs**

*QMS – quadrapole mass spectrometer*

*FTIR – Fournier Transfer InfraRed (spectrometer)*

## N<sub>2</sub>O Decomposition Byproducts

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- NO : NO<sub>2</sub> ratio changes
  - NO<sub>x</sub> abated in strongly reducing environment
    - More fuel
  - Significant Products of Incomplete Combustion (PICs) – CO, CH<sub>4</sub>
    - Less fuel
- NO and NO<sub>2</sub> formation in the abatement?
  - NO<sub>x</sub> levels can increase in oxidizing combustor
- EFs are required to evaluate NO<sub>x</sub> from abatement
  - Differentiate process NO<sub>x</sub> from abatement NO<sub>x</sub>

# Varying Flows of N<sub>2</sub>O During Recipe

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- Some recipes have widely-ranging N<sub>2</sub>O flows
  - High N<sub>2</sub>O setup produces PICs at low N<sub>2</sub>O
  - Low N<sub>2</sub>O setup produces poor DRE high N<sub>2</sub>O
- No generalized setting for N<sub>2</sub>O abatement
  - Interactive abatement systems that respond to N<sub>2</sub>O flows
  - Need tie in to process gas flows and EFs for best performance
- Process gases can affect N<sub>2</sub>O DRE
  - E.g. TEOS makes ethanol and CO
    - These act as fuels

## NF<sub>3</sub> – Based Chamber Cleans

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- NF<sub>3</sub> abatement has different abatement requirements
  - Fuel injection used for N<sub>2</sub>O
  - High fuel on NF<sub>3</sub> chamber clean ( $2 \text{ NF}_3 \rightarrow 3 \text{ F}_2 + \text{ N}_2$ ) makes CF<sub>4</sub>
    - $\text{CH}_4 + 4 \text{ F}_2 \rightarrow \text{CF}_4 + 4 \text{ HF}$
    - This has been well-documented
  - Need interface to indicate clean step
- Tool interface required for N<sub>2</sub>O and NF<sub>3</sub>
  - Only way to optimize both Dep and Clean steps
    - Else you make more CF<sub>4</sub> (high GWP) than you save by abating N<sub>2</sub>O

# Summary for N<sub>2</sub>O Abatement

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## Good News

- **N<sub>2</sub>O is readily abated using combustion to > 95% DRE**
  - Proper combustor chemistry (CH<sub>4</sub>, O<sub>2</sub>) critical
  - Minimize NO<sub>x</sub> and CO emissions

## More Work

- Need for emission factors for N<sub>2</sub>O processes
- Need interfacing with tool to indicate process gas flows
- Expand to evaluate all N<sub>2</sub>O processes